

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

	Sylvia H. Pas	Examiner: TBD
Serial No:	TBD	Art Unit: TBD
Filed:	01/11/01	Docket No.: TI-22398
For:	SYSTEM AND METHOD FOR INTEGRATED OXIDE REMOVAL AND PROCESSING OF A SEMICONDUCTOR WAFER	

PRELIMINARY AMENDMENT

January 11, 2001

Assistant Commissioner for Patents

Washington, DC 20231

Dear Sir:

Please amend the above referenced application as follows:

In the Specification:

Page 1, before line 1, insert --This application claims priority under 35 USC §
119(e)(1) of provisional application numbers **60/178,647** filed **01/28/00**.--

REMARKS

Entry of the foregoing amendment prior to examination is respectfully requested.

If the Examiner has any questions or other correspondence regarding this application, Applicant requests that the Examiner contact Applicant's attorney at the below listed telephone number and address.

Respectfully submitted,



Jacqueline J. Garner
Attorney for Applicants
Reg. No. 36,144

Texas Instruments Incorporated
P. O. Box 655474, MS 3999
Dallas, Texas 75265
(972) 271-1176
Fax: (972) 917-4417
or (972) 917-4418

FOR FILING